

What is claimed is:

1. A piezoelectric device for an injector, built into an injector and generating driving force of said injector, characterized in that:

5 said piezoelectric device is fabricated by alternately laminating a plurality of piezoelectric layers generating displacement in proportion to an applied voltage and a plurality of internal electrode layers for supplying the applied voltage; and

10 in said piezoelectric device, a relation $d(0.1E_c)/d(1.2E_c) > 0.43$ is established, where E_c is coercive electric field which causes the changing of polarizing direction, between an apparent piezoelectric constant $d(1.2E_c)$ calculated from static elongation when
15 an electric field of $1.2 E_c$ is applied to said piezoelectric device in the same direction as a polarizing direction while a preset load of 500 N is applied to said piezoelectric device, and an apparent piezoelectric constant $d(0.1E_c)$ calculated from static
20 elongation when an electric field of $0.1 E_c$ is applied to said piezoelectric device in the same direction as the polarizing direction.

2. A piezoelectric device for an injector according to claim 1, wherein a relation
25 $d(0.1E_c)/d(1.2E_c) \geq 0.5$ is established between said piezoelectric constant $d(1.2E_c)$ and said piezoelectric constant $d(0.1E_c)$.

3. A piezoelectric device for an injector, built into an injector and generating driving force of said
30 injector, characterized in that:

 said piezoelectric device is fabricated by alternately laminating a plurality of piezoelectric layers generating displacement in proportion to an applied voltage and a plurality of internal electrode
35 layers for supplying the applied voltage; and

 said piezoelectric device has a change ratio of displacement of 9% or below when a frequency of

the applied voltage is changed from 1 Hz to 200 Hz under the state where an AC voltage is applied so that an electric field intensity of 0 to 1.5 kV/mm is generated by a sine wave while a preset load of 500 N is applied to said piezoelectric device.

4. A piezoelectric device for an injector according to claim 1, wherein said change ratio of displacement is 7% or below.

5. A piezoelectric device for an injector, built in an injector and generating driving force of said injector, characterized in that:

said piezoelectric device is fabricated by alternately laminating a plurality of piezoelectric layers generating displacement in proportion to an applied voltage and a plurality of internal electrode layers for supplying the applied voltage; and

in said piezoelectric device, displacement increases with the rise of temperature within the range of -40°C to 150°C .

6. A piezoelectric device for an injector according to claim 5, wherein said change ratio of displacement is 5 to 40% within the range of temperature of -40°C to 150°C .

7. A piezoelectric device for an injector, built in an injector and generating driving force of said injector, characterized in that:

said piezoelectric device is fabricated by alternately laminating a plurality of piezoelectric layers generating displacement in proportion to an applied voltage and a plurality of internal electrode layers for supplying the applied voltage; and

said piezoelectric device has a dielectric loss of 8% or below calculated from a P-E hysteresis.

8. A piezoelectric device for an injector according to claim 7, wherein said dielectric loss is 7% or below.

9. A piezoelectric device for an injector built in

an injector and generating driving force of said injector, characterized in that:

said piezoelectric device is fabricated by alternately laminating a plurality of piezoelectric layers expanding and contracting in proportion to an applied voltage and a plurality of internal electrode layers for supplying the applied voltage;

the sectional shape of said piezoelectric device crossing at right angles the laminating direction is an octagon or a polygon with a larger number of sides than octagon; and

said piezoelectric device is accommodated in a cylindrical accommodation space.

10. A piezoelectric device for an injector according to claim 9, wherein a proximity ratio expressed by $(B/A) \times 100 (\%)$, where A is a length of the whole circumference of a circumscribed circle of said piezoelectric device and B is the sum of length of circumferential portions having a distance of 0.2 mm or below between said circumscribed circle and said piezoelectric device, is larger than 17%.

11. A piezoelectric device for an injector according to claim 9, wherein a proximity ratio expressed by $(B/A) \times 100 (\%)$, where A is a length of the whole circumference of a circumscribed circle of said piezoelectric device and B is the sum of length of circumferential portions having a distance of 0.2 mm or below between said circumscribed circle and said piezoelectric device, is 32% or more.

12. A piezoelectric device for an injector according to claim 9, wherein at least two side surface flat portions having a width of 2.5 mm or more are disposed on a side surface parallel to said laminating direction.

13. A piezoelectric device for an injector according to claim 9, wherein an insulating film having a thickness of 0.002 to 0.5 mm is formed at least on the

surface of a side surface parallel to the laminating direction.

5 14. A piezoelectric device for an injector according to claim 13, wherein a value $R2 - R1$, where $R1$ is a maximum outer diameter of said piezoelectric device inclusive of said insulating member and $R2$ is an inner diameter of said circular cylindrical accommodation space, is 0.5 mm or below.

10 15. A piezoelectric device for an injector according to claim 13, wherein said insulating film is made of any of a silicone resin, a polyimide resin, an epoxy resin and a fluorocarbon resin.

15 16. A piezoelectric device for an injector according to claim 9, wherein electrode take-out portions electrically connected to said internal electrode layers are disposed on a distal end face and a rear end face of said piezoelectric device in the laminating direction, respectively.

20 17. A piezoelectric device for an injector according to claim 9, wherein two electrode take-out portions electrically connected to said internal electrode layer are disposed on either one of a distal end face and a rear end face of said piezoelectric device in the laminating direction.

25 18. A piezoelectric device for an injector according to claim 16, wherein at least one of said electrode take-out portions is electrically connected to at least one of said internal electrode layers through a through-hole formed in said piezoelectric layer.

30 19. A piezoelectric device for an injector according to claim 16, wherein at least one of said electrode take-out portions is electrically connected to a side surface disposed on said side surface of said piezoelectric device.

35 20. A piezoelectric device for an injector built in an injector and generating driving force of said injector, characterized in that:

said piezoelectric device is fabricated by alternately laminating a plurality of piezoelectric layers expanding and contracting in proportion to an applied voltage and a plurality of internal electrode layers for supplying the applied voltage;

at least a part or the whole of the sectional shape of said piezoelectric device crossing at right angles the laminating direction is arcuate; and

said piezoelectric device is accommodated in a circular cylindrical accommodation space.

21. A piezoelectric device for an injector according to claim 20, wherein a proximity ratio expressed by $(B/A) \times 100 (\%)$, where A is a length of the whole circumference of a circumscribed circle of said piezoelectric device and B is the sum of length of circumferential portions having a distance of 0.2 mm or below between said circumscribed circle and said piezoelectric device, is larger than 17%.

22. A piezoelectric device for an injector according to claim 20, wherein a proximity ratio expressed by $(B/A) \times 100 (\%)$, where A is a length of the whole circumference of a circumscribed circle of said piezoelectric device and B is the sum of length of circumferential portions having a distance of 0.2 mm or below between said circumscribed circle and said piezoelectric device, is 32% or more.

23. A piezoelectric device for an injector according to claim 20, wherein at least two side surface flat portions having a width of 2.5 mm or more are disposed on the side surface parallel to the laminating direction.

24. A piezoelectric device for an injector according to claim 20, wherein an insulating film having a thickness of 0.002 to 0.5 mm is formed on at least the surface of the side surface parallel to the laminating direction of said piezoelectric device.

25. A piezoelectric device for an injector

according to claim 24, wherein a value $R2 - R1$, where $R1$ is a maximum outer diameter of said piezoelectric device inclusive of said insulating member and $R2$ is an inner diameter of said cylindrical accommodation space, is 0.5 mm or below.

26. A piezoelectric device for an injector according to claim 24, wherein said insulating film is made of any of a silicone resin, a polyimide resin, an epoxy resin and a fluorocarbon resin.

27. A piezoelectric device for an injector according to claim 20, wherein electrode take-out portions electrically connected to said internal electrode layers are disposed on a distal end face and a rear end face of said piezoelectric device in the laminating direction, respectively.

28. A piezoelectric device for an injector according to claim 20, wherein two electrode take-out portions electrically connected to said internal electrode layer are disposed on either one of a distal end face and a rear end face of said piezoelectric device in the laminating direction.

29. A piezoelectric device for an injector according to claim 27, wherein at least one of said electrode take-out portions is electrically connected to at least one of said internal electrode layers through a through-hole formed in said piezoelectric layer.

30. A piezoelectric device for an injector according to claim 27, wherein at least one of said electrode take-out portions is electrically connected to a side surface disposed on said side surface of said piezoelectric device.